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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroaki TAKEUCHI, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HEREWITH

INTERNATIONAL APPLICATION NO.: PCT/JP05/02425

INTERNATIONAL FILING DATE: February 17, 2005

FOR: METHOD FOR PRODUCING SILICON OXIDE FILM

REQUEST FOR PRIORITY UNDER 35 U.S.C. 119
AND THE INTERNATIONAL CONVENTION

Commissioner for Patents
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that the applicant claims as priority:

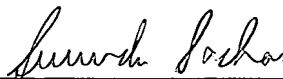
COUNTRY
Japan

APPLICATION NO
2004-040613

DAY/MONTH/YEAR
17 February 2004

Certified copies of the corresponding Convention application(s) were submitted to the International Bureau in PCT Application No. PCT/JP05/02425.

Respectfully submitted,
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